



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

MIMURA, *et al.*

Serial No.: 10/647,433

Filed: 26 August 2003

For: SILICON ETCHING METHOD

Art Unit: 1765

Examiner: Tran, Binh X.

Atty. Dckt: 033082M172

**RESPONSE UNDER 37 C.F.R. § 1.111**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**Mail Stop: Amendment**

Dear Sir:

This is in response to the Office action mailed October 12, 2005, to which the time for response was set to expire January 12, 2006. A Petition for a Three-Month Extension of Time and the requisite fee are submitted herewith to extend the due date for response to April 12, 2006. Claims 1-19 are pending. Claim 16 is withdrawn. Claims 8 and 11-13 were objected to and claims 1-7, 9, 10, 14, 15 and 17-19 are rejected. Reconsideration and entry of the following amendment(s) are respectfully requested.

Amendment to the Claims begins on page 2 of this paper.  
Remarks begin on page 5 of this paper.